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PATENT
2658-247P

IN THE U.S. PATENT AND TRADEMARK OFFICE

Applicants: Soon Ho CHOI et al. Conf.: 1195
Serial No.: 09/731,738 Art Unit: 1765
Filed: December 8, 2000 Examiner: D. Deo
For: WET ETCHING APPARATUS AND METHOD

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AMENDMENT UNDER 37 C.F.R. §1.111

Assistant Commissioner for Patents
Washington, DC 20231

March 3, 2003

Sir:

In response to the Office Action mailed November 4, 2002 (Paper No. 5), the following amendments and remarks are respectfully submitted in connection with the above-identified application:

In the Claims:

Please ~~cancel~~ ☒ **claims 13-17** without prejudice to or disclaimer of the subject matter contained therein.

Please **rewrite claims 8 and 18** as follows:

A1
8. (Amended) The apparatus according to claim 6, wherein the ultraviolet cleaner is installed at a predetermined area in the loader on which a plurality of cassettes arranged with the substrate are loaded.

18. (Amended) The apparatus according to claim 1, further comprising:

flowing an etchant on the substrate in a tilt drain part;

A2 eliminating the etchant on the substrate in a de-ionized
rinse part having a de-ionized water; and

drying the de-ionized water in a spin drier.



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MARKED-UP COPY OF AMENDMENTS

Please **cancel claims 13-17** without prejudice or disclaimer.

Please **amend claims 8 and 18** as follows:

8. (Amended) The apparatus according to claim 6, wherein the ultraviolet cleaner is installed at a predetermined area in the loader [on the substrate having] on which a plurality of cassettes arranged with the substrate are loaded.

18. (Amended) The apparatus according to claim [15] 1, further comprising:

flowing an etchant on the substrate in a tilt drain part;

eliminating the etchant on the substrate in a de-ionized rinse part having a de-ionized water; and

drying the de-ionized water in a spin drier.

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